

R. E. Fuller

Group Art Unit: 2851

Docket No.: 108455

Examiner:

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

e the Application of

Yasuhiro OMURA et al.

Application No.: 09/769,832

Filed: January 26, 2001

PROJECTION EXPOSURE APPARATUS AND METHOD, CATADIOPTRIC OPTICAL

SYSTEM AND MANUFACTURING METHOD OF DEVICES

INFORMATION DISCLOSURE STATEMENT

Director of the U.S. Patent and Trademark Office Washington, D.C. 20231

Sir:

For:

Pursuant to 37 CFR §1.56, the attention of the Patent and Trademark Office is hereby directed to the reference(s) listed on the attached PTO-1449. Unless otherwise indicated herein, one copy of each reference is attached. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the reference(s) be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

冈 1. This Information Disclosure Statement is being filed (a) within three months of the U.S. filing date of this non-CPA application, OR (b) before the mailing date of a first Office Action on the merits in the present application. No certification or fee is required.

 \bowtie 2. English-language Abstracts of the non-English language reference are attached hereto.

Respectfully submitted,

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MAC:RZE/dmw

Date: September 24, 2002

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